

Title (en)

METHOD FOR CMP OF LOW DIELECTRIC CONSTANT POLYMER LAYERS

Title (de)

VERFAHREN FÜR CMP VON NIEDERDIELEKTRIZITÄTSKOEFFIZIENTEN POLYMERSCHICHTEN

Title (fr)

PROCEDE DE POLISSAGE CHIMIQUE-MECANIQUE DE COUCHES POLYMERES CONSTANTES FAIBLEMENT DIELECTRIQUES

Publication

EP 1171906 A1 20020116 (EN)

Application

EP 00913478 A 20000216

Priority

- US 0003893 W 20000216
- US 12056799 P 19990218

Abstract (en)

[origin: WO0049647A1] A method for chemical-mechanical polishing of a low dielectric constant polymeric layer wherein a slurry comprising high purity fine metal oxide particles uniformly dispersed in a stable aqueous medium is used.

IPC 1-7

H01L 21/302

IPC 8 full level

C09G 1/02 (2006.01); **H01L 21/3105** (2006.01); **H01L 21/321** (2006.01)

CPC (source: EP KR)

C09G 1/02 (2013.01 - EP); **H01L 21/304** (2013.01 - KR); **H01L 21/31058** (2013.01 - EP); **H01L 21/3212** (2013.01 - EP)

Citation (search report)

See references of WO 0049647A1

Designated contracting state (EPC)

DE FR GB IT

DOCDB simple family (publication)

WO 0049647 A1 20000824; EP 1171906 A1 20020116; JP 2002537652 A 20021105; KR 20010111261 A 20011217

DOCDB simple family (application)

US 0003893 W 20000216; EP 00913478 A 20000216; JP 2000600297 A 20000216; KR 20017010397 A 20010816